

ABSTRACT

A stamper with a sharp uneven pattern ~~is obtained, and~~ for manufacturing high precision information media can be manufactured using this stamper.

~~—A—~~ A and a method of manufacturing a ~~stamper comprises the steps of~~ stamper. The method includes (1) manufacturing a photoresist ~~master 100~~ master by forming a light absorption ~~layer 103~~ layer and a photoresist ~~layer 104~~ layer on ~~top of a substrate 102,~~ substrate, (2) forming a latent image on the photoresist ~~layer 104,~~ layer, and ~~then forming an uneven pattern 106~~ pattern in the photoresist ~~layer 104~~ layer by developing the latent image, (3) forming a Ni thin ~~film 108~~ film on the uneven ~~pattern 106~~ pattern of the photoresist ~~master 100~~ master by electroless plating, (4) forming a Ni ~~film 110~~ film on ~~top of the Ni thin film 108,~~ film, and (5) ~~then removing the Ni thin film 108~~ film and the Ni ~~film 110~~ film from the photoresist ~~master 100~~ master. ~~to form the stamper 120, wherein~~ The method also includes, as ~~preliminary treatments prior to the step of forming the Ni thin film 108~~ film on the photoresist ~~layer 104,~~ layer, a metal catalyst ~~is being~~ is being provided on the surface of the uneven ~~pattern 106,~~ pattern, the metal catalyst ~~is being~~ is being activated, and the surface of the uneven ~~pattern 106~~ pattern ~~on which the metal catalyst has been provided is being~~ is being washed with ultra pure water.